

The ATLAS Insertable B-layer (IBL) project

Alessandro La Rosa/ U. Geneva (CH)
on behalf of the ATLAS Pixel Collaboration

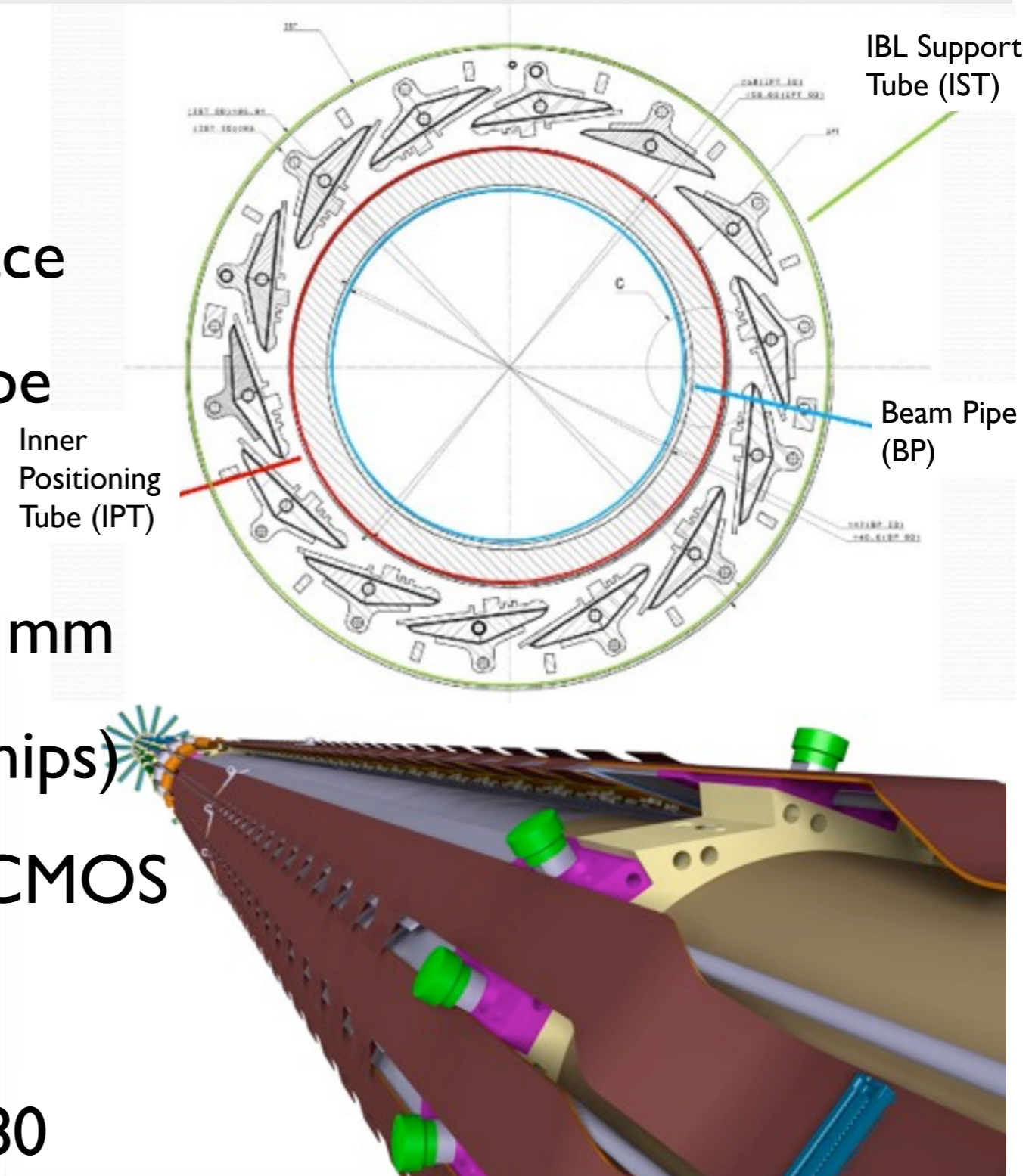
The Insertable B-Layer (IBL)

- **Motivation:**

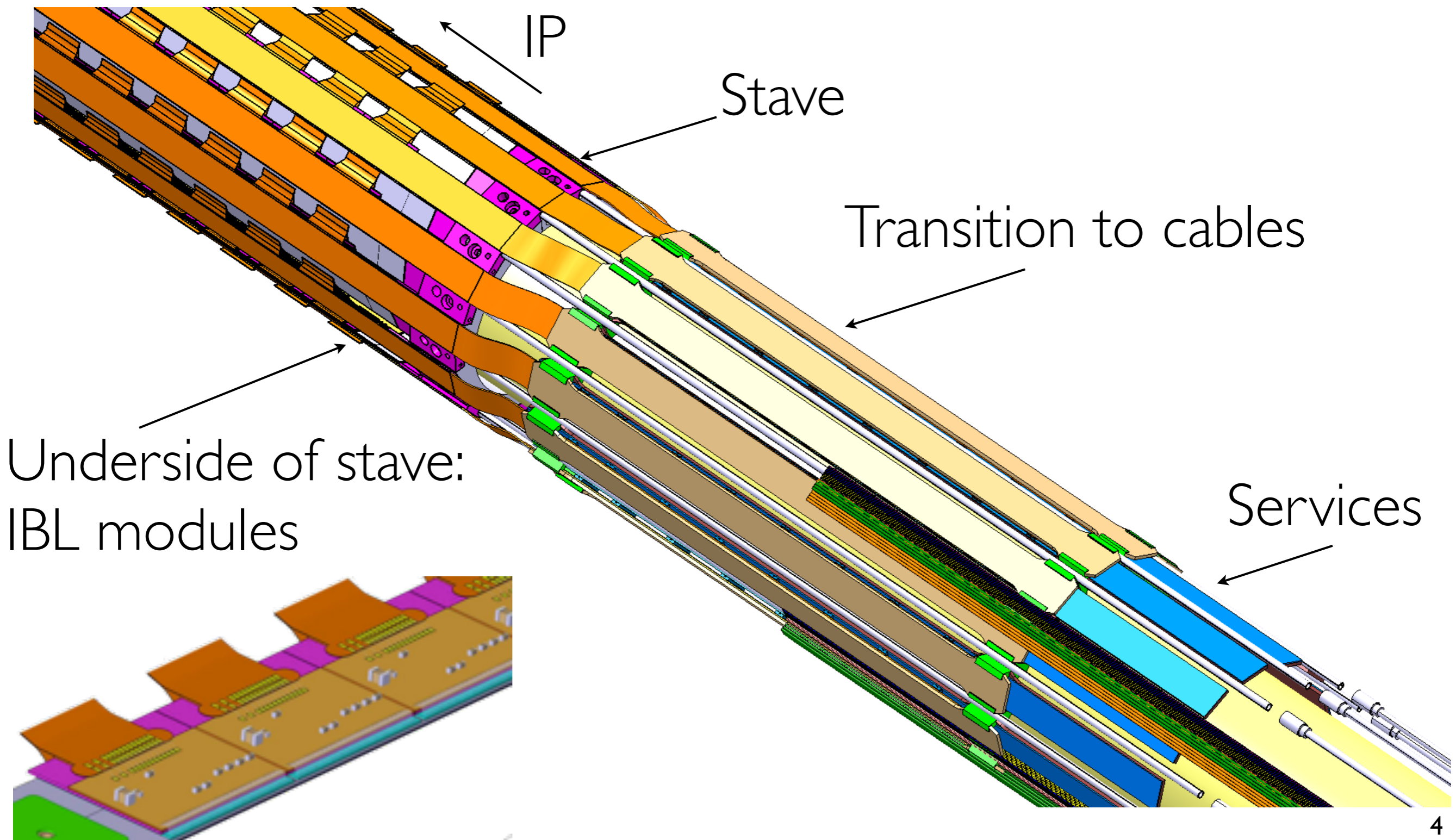
- Excellent vertex detector performance is crucial
 - ▶ improve heavy flavor tagging, primary and secondary vertex reconstruction/ separation
- Additional innermost layer will boost tracking performance
 - ▶ adds additional redundancy of the detector in case of radiation damage
- Originally scheduled for LS-2 (2016) then LS-2 was postponed to 2017-18, so that: advance the IBL project schedule and instal it in LS-1 (2013-14)

The Insertable B-Layer (IBL)

- Layout based on performance studies in G4 and available space
- IBL mounted on new beam pipe
- Length: ~ 64cm
- Envelope: $R_{in}=31$ mm, $R_{out}=40$ mm
- **14 stave** (each stave 32 FEI4 chips)
- FEI4 R/O chip in IBM 130nm CMOS
 - cell size: 50um x 250um
 - 80 (col) x 336 (row) = 26880



Stave and module arrangement



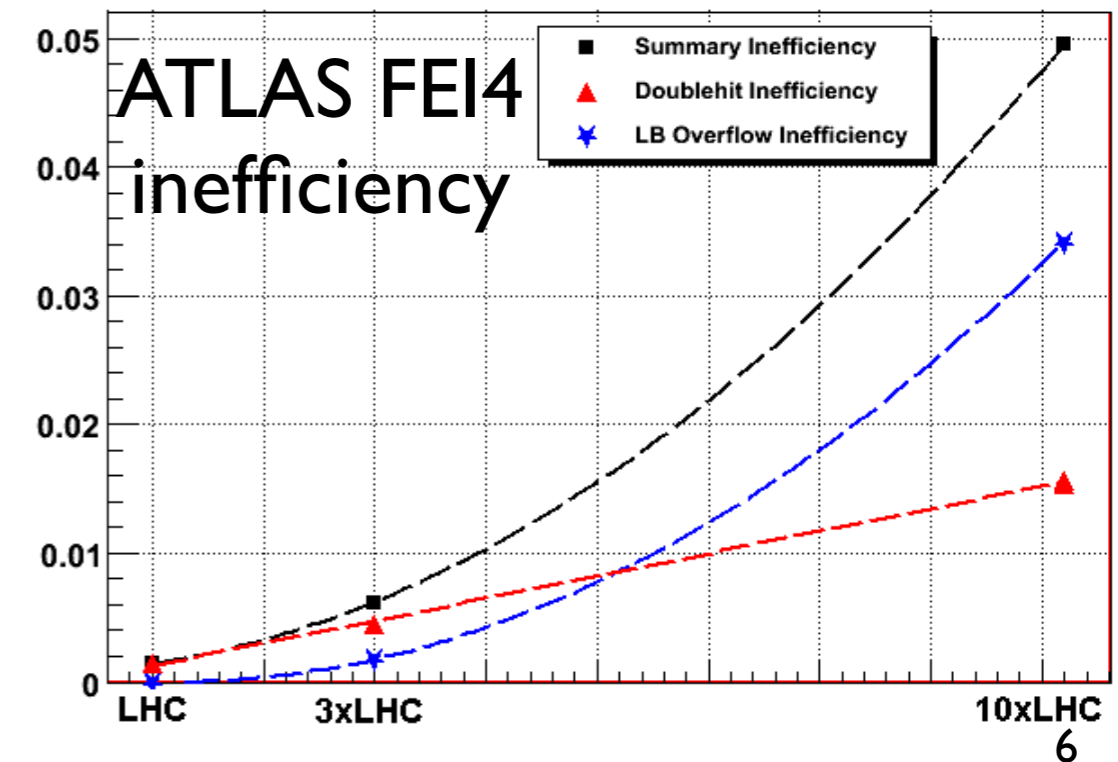
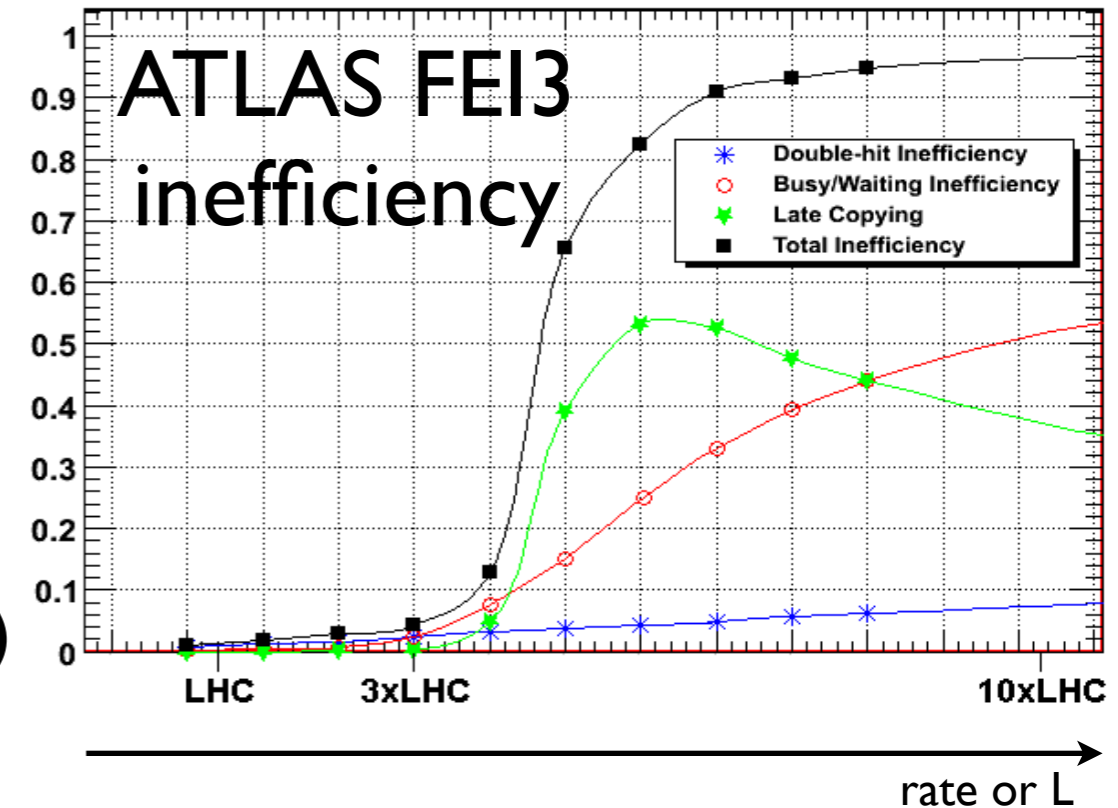
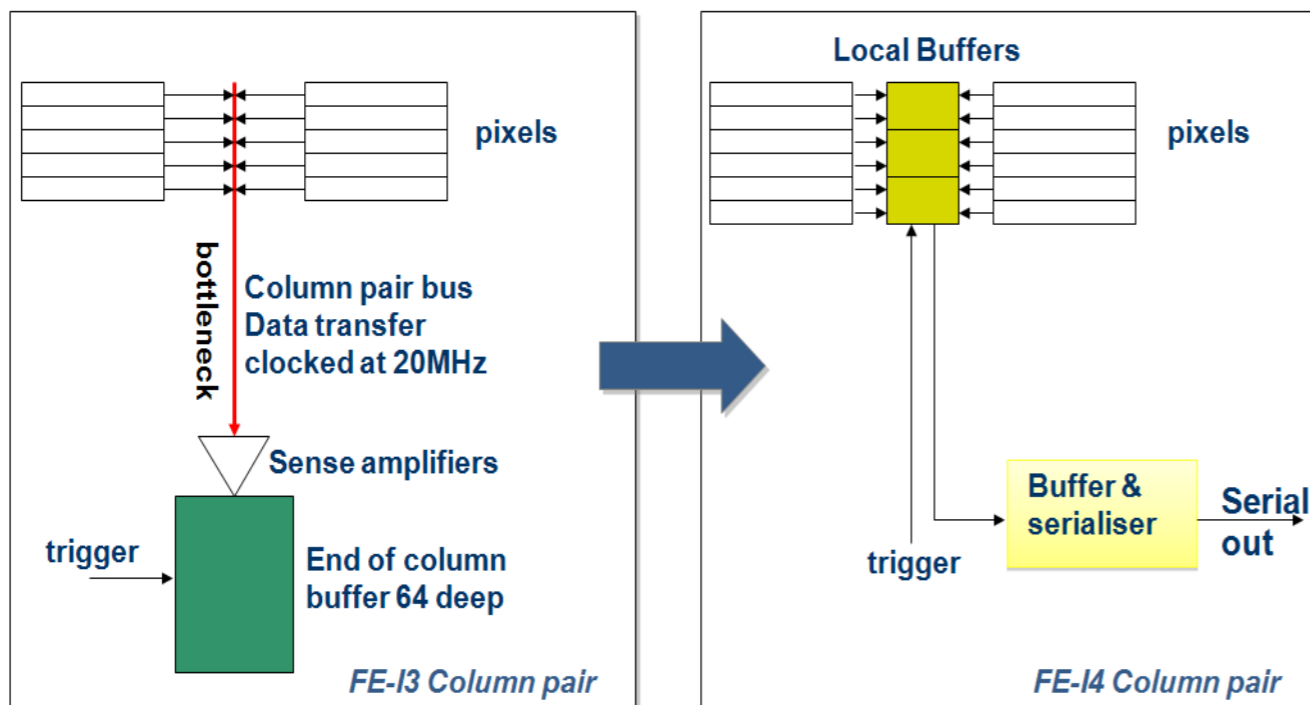
IBL is also a tech step to HL-LHC

- Sensor with an higher radiation hardness
 - 5×10^{15} n_{eq}/cm² NIEL (improved radiation hardness by factor 5)
- New readout chip (FEI4) with finer segmentation, larger active fraction and increased hit-rate capability
 - new readout architecture and smaller cell size 250x50 μm²
 - large single-chip (21x19 mm²)
- Lighter detector: less radiation length in support and cooling
 - improve radiation length per layer from 2.7% to ~1.9% to minimize multiple scattering in closest layer
 - high efficiency CO₂ cooling at -40 °C coolant temperature
- New off-detector readout system
 - matched to FEI4 pixel chip
 - increase readout speed by a factor 2

The FEI4 readout chip

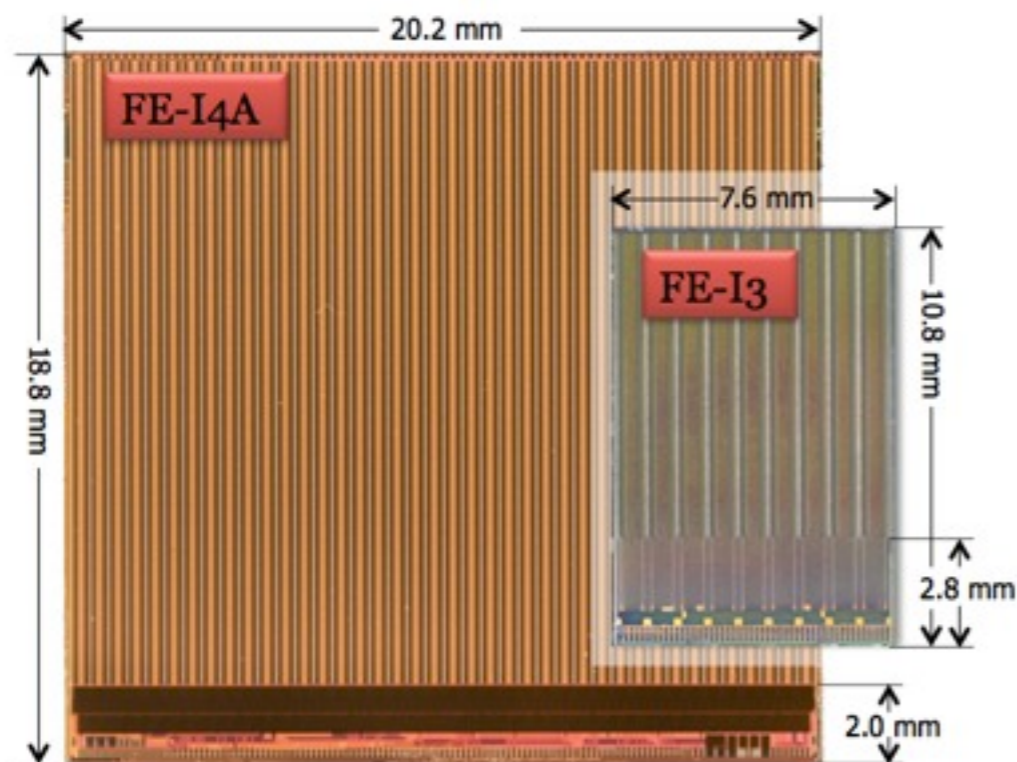
- Motivation

- FEI3 inefficiency rises steeply with the hit rate.
- bottleneck: congestion in double column readout \sim way-out:
 - ▶ more local in-pixel storage (130nm)
 - ▶ data storage made locally at the PXL level unit until triggered



The FEI4 readout chip

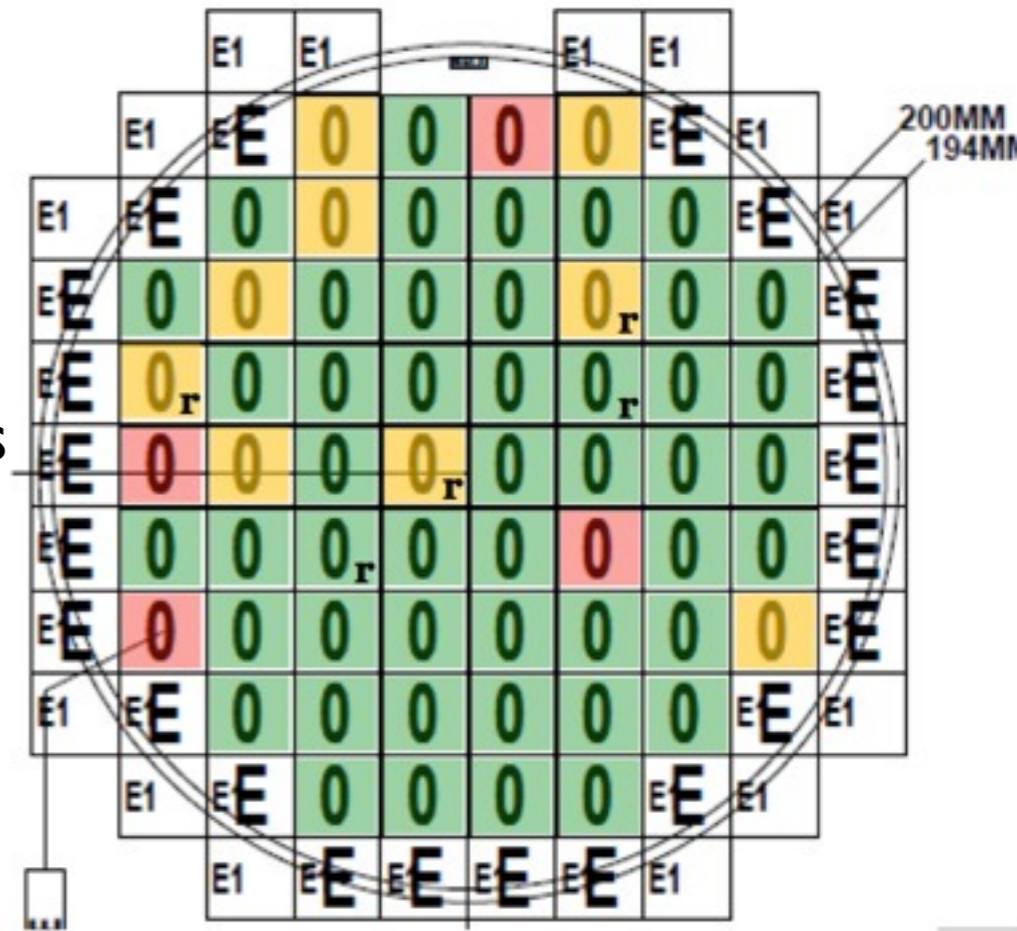
- FEI4 in IBM 130nm CMOS
 - array size: 80 (col) x 336 (row)
 - average hit rate at 1% inefficiency = 400 MHz/cm²; max trigger rate: 200kHz
 - Fully qualified up to 250 Mrad (few samples irradiated to 750 Mrad and working!): after receiving 3x lifetime expected dose, some dead/noisy pixel were observed, most of which were recovered by retuning the FE
 - extensive use of *dual interlocked storage cells* (DICE) for critical configuration information. Tests performed at CERN PS w/ 24 GeV protons. The SEU cross-section of hardened cells are $\sim 10^{-15}$ cm⁻² per DICE bit



	FE-I3	FE-I4
Pixel size [μm^2]	50x400	50x250
Pixel array	18x160	80x336
Chip size [mm^2]	7.6x10.8	20x19
Active fraction	74%	89%
Analog current [$\mu\text{A}/\text{pix}$]	26	10
Digital current [$\mu\text{A}/\text{pix}$]	17	10
Analog Voltage [V]	1.6	1.4
Digital Voltage [V]	2.0	1.2
Total power [$\mu\text{W}/\text{pix}$]	75	26
Pseudo-LVDS out [Mb/s]	40	160

FEI4 pre-production

- FEI4-A wafers received in late 2010 and used as first chip-test, IBL module prototyping and sensor/ module qualification throughout all 2011/2012
 - ▶ the first fully integrated chip was a big success
 - ▶ demonstrated good analog behavior with several different sensor technologies (silicon planar/3d and pCVD diamond)
 - ▶ demonstrated digital functionality needed for IBL
- Good chip yield approx $\frac{2}{3}$ (i.e. ~40/wafer)
- Demonstrated bump-bonding on very large & thin chip at IZM
- **Built first IBL modules with full IBL specs !**



Based on the prototype studied, minor design changes was implemented for the production FE iteration (FEI4-B)

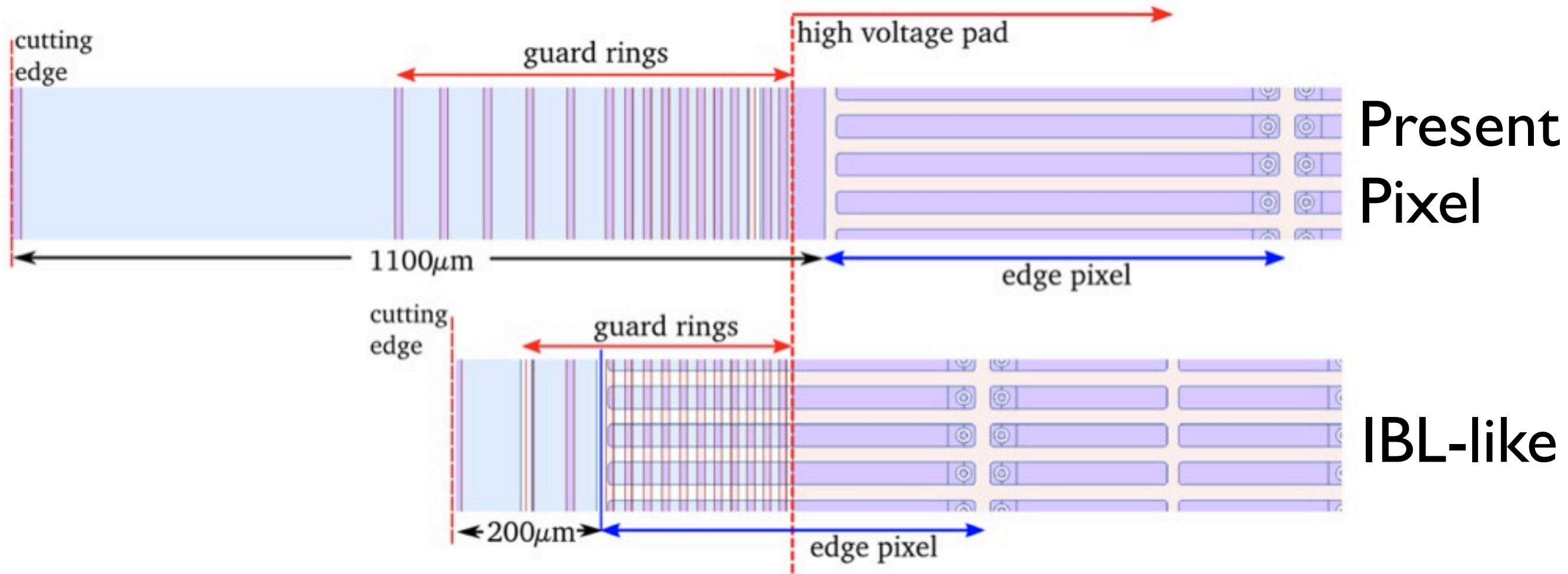
FEI4 production

- Two fabrication runs: Engineering & Production
 - a change was made to one via mask for production run, to patch an ESD protection deficiency in the digital voltage regulator
- Scale of the production: **a total of 134 FEI4-B wafers have been purchased & received !!!**
 - at 60% yield, that amounts to 1.6m² of detector grade active area. This is the same active area as the present pixel detector, and nearly as many channels as ATLAS and CMS combined

The IBL sensor technologies

- Several promising new sensor technologies have been developed so far:
 - Planar n-in-n and n-in-p
 - 3D full & active-edge and double-side & slim-edge
 - pCVD diamond
- Because of the tight IBL construction schedule, the slim-edge *Planar n-in-n* and the *3D double-side* silicon technologies have been retained for prototyping with the FEI4 in view of the IBL construction
 - pCVD is employed for ATLAS DBM (no covered in this talk)

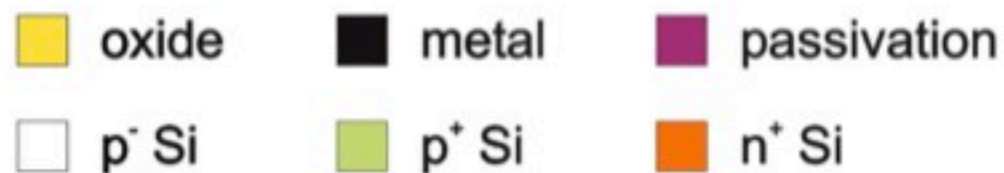
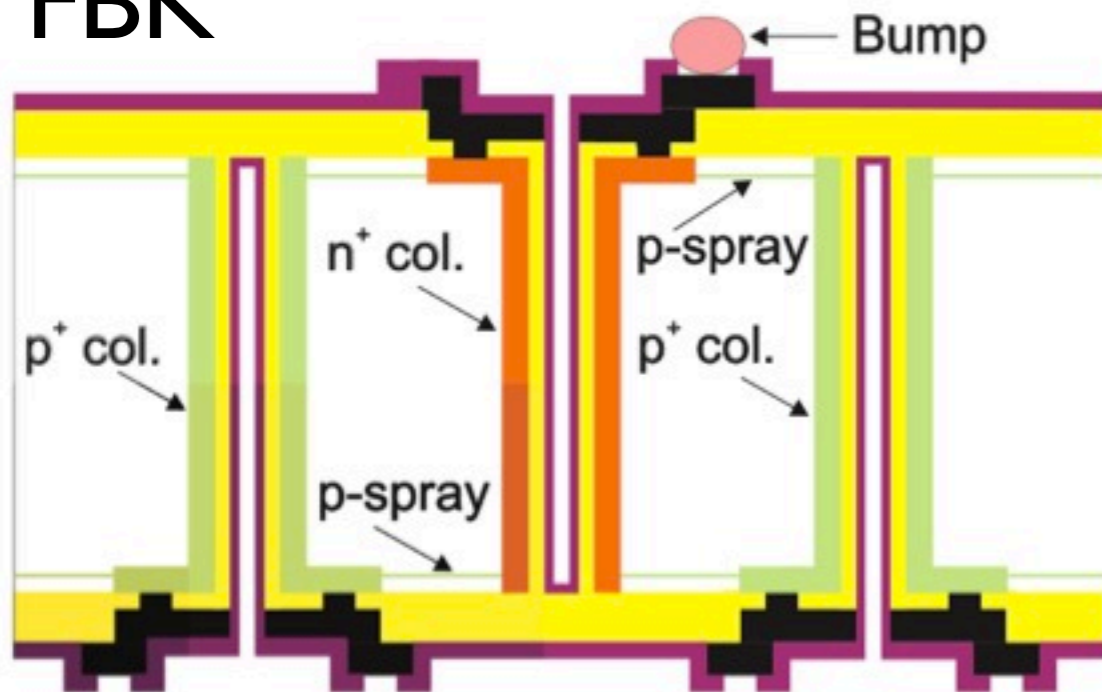
The IBL Planar n-in-n



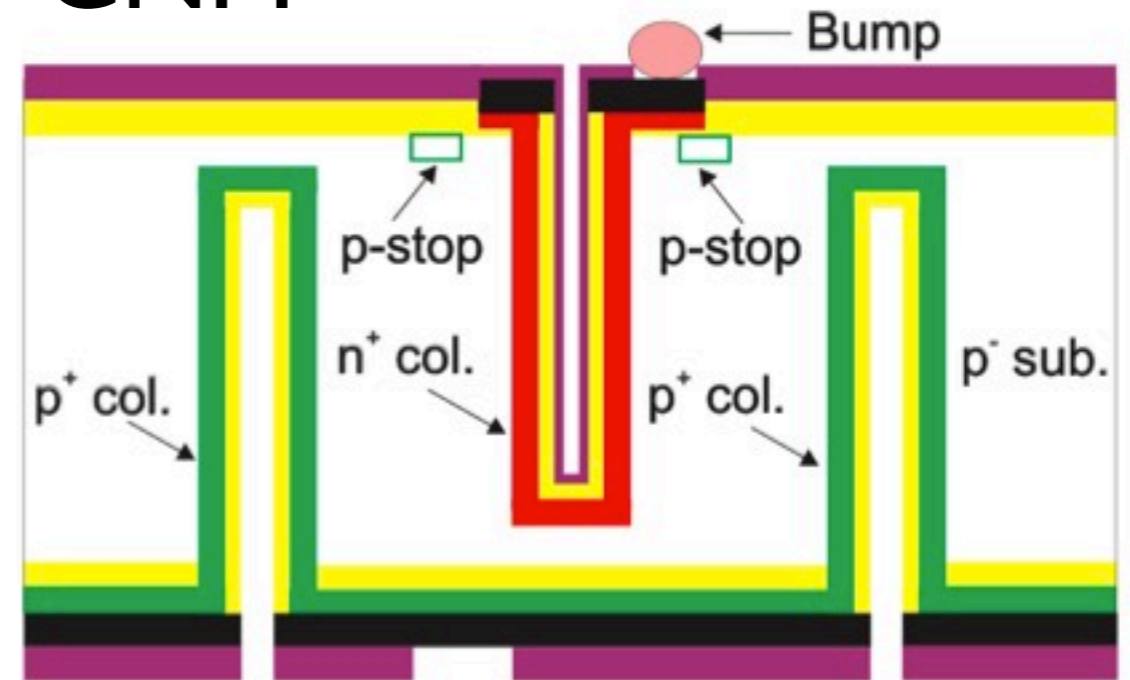
- 200 μm thick oxygenated n⁺-in-n planar sensor
- inactive edge minimized by shifting guard-rings (13) underneath active pixel region
- manufactured at CiS as the present Pixel sensor

The IBL 3D n-in-p

FBK



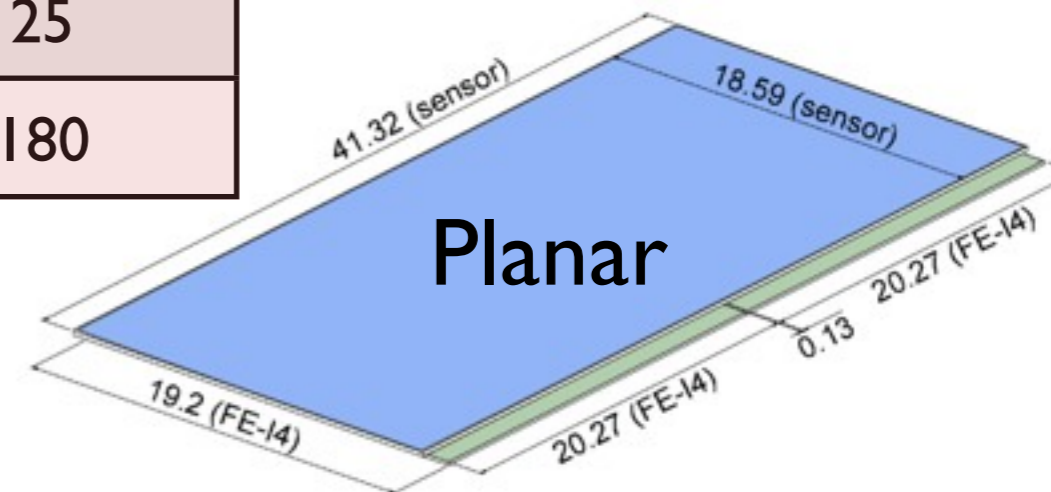
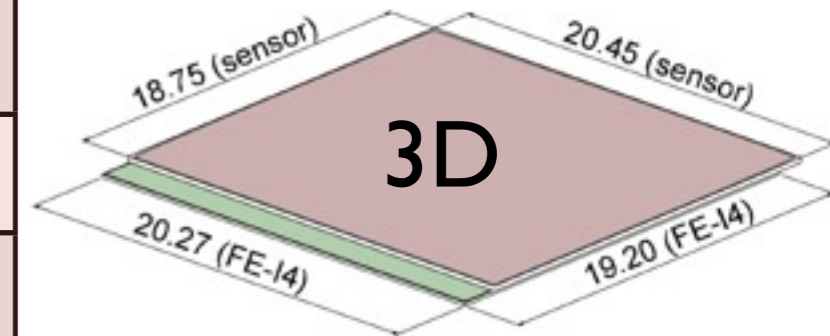
CNM



- 230 μm thick 3D p-type sensors
- column through ~full bulk with two electrodes per pixel (so called: 2E-type)
- depletion horizontally (short depletion width leads to low bias voltages)
- manufactured at FBK and CNM

The IBL sensors specs

	Planar	3D
Active size W x L [mm ²]	16.8 x 40.9	16.8 x 20.0
Total size W x L [mm ²]	18.59 x 41.32	18.75 x 20.45
Thickness [mm]	0.20	0.23
Typical depletion voltage [V]	< 35	< 15
Typical initial operation voltage [V]	60 (V _{dep} + 30V)	25
At of at end of lifetime [V]	1000	180



- Sensors specification for IBL

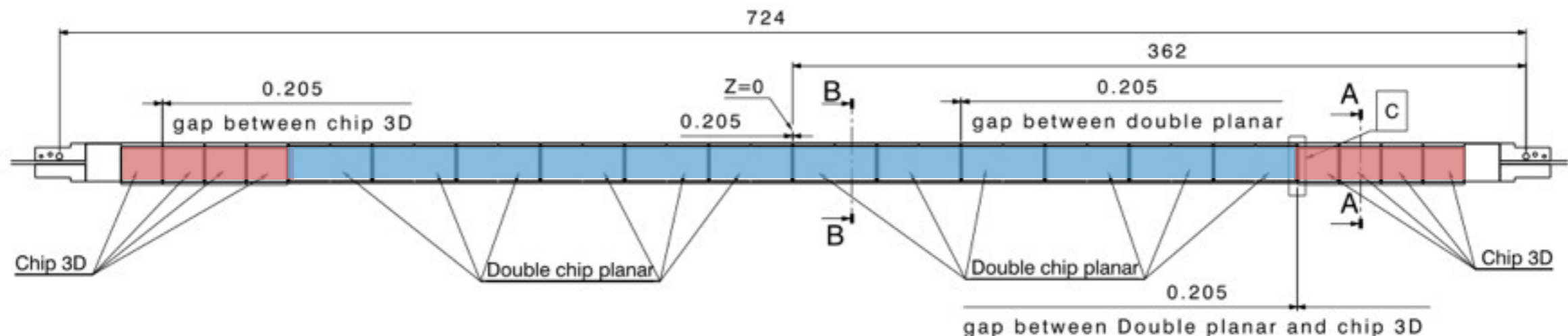
- qualify to $5 \times 10^{15} \text{ n}_{\text{eq}} \text{ cm}^{-2}$
- sensor max power dissipation: 200 mW/cm² at -15 °C
- single-hit efficiency > 97%

Module production for IBL

- IBL will build $\sim 2x$ number of installed modules
- ATLAS Pixel extended Institute Board endorsed the recommendation of the review panel (July 2011):
 - produce enough Planar sensors to build 100% of the IBL
 - produce 3D sensor to build of 25% of the IBL

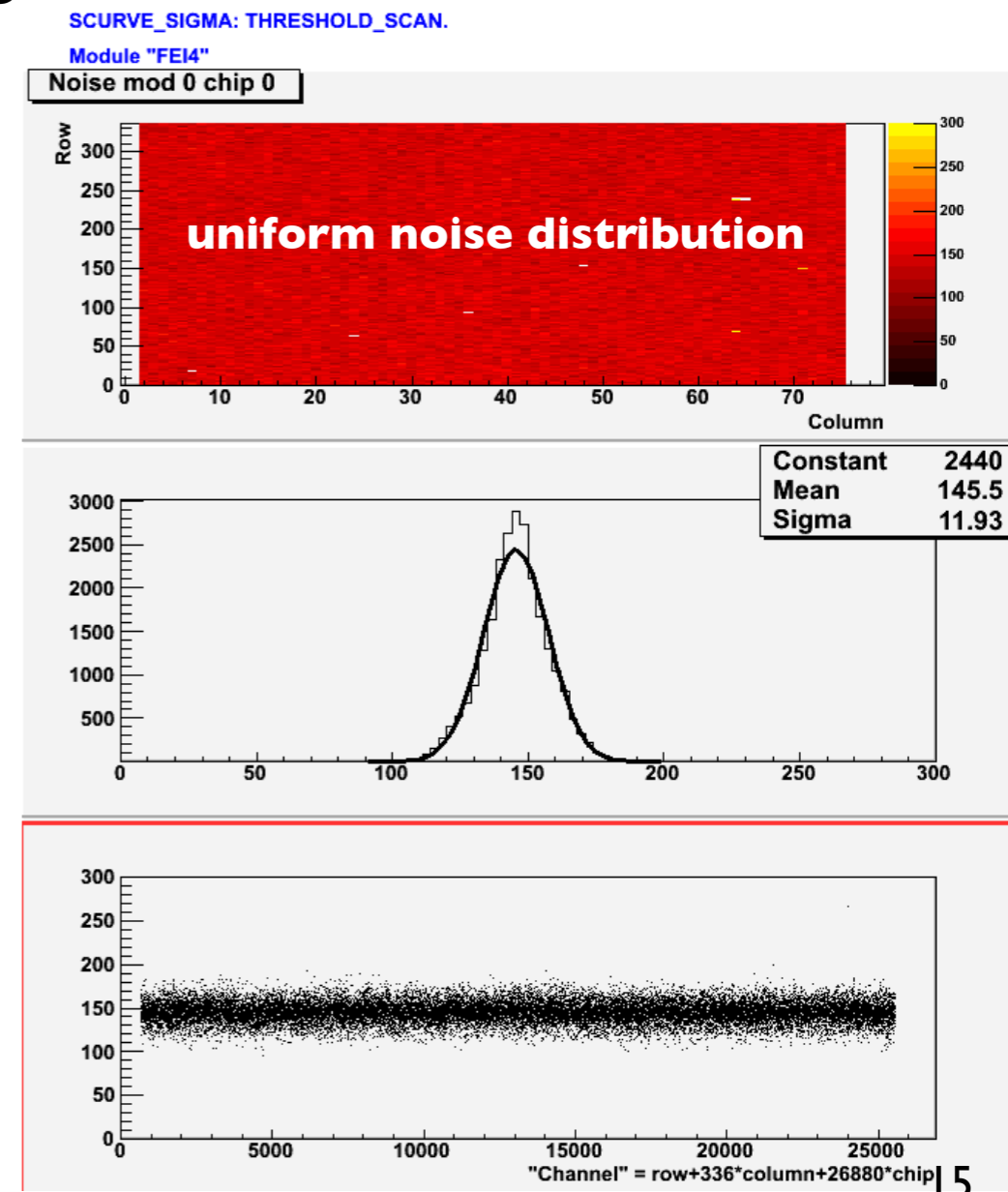
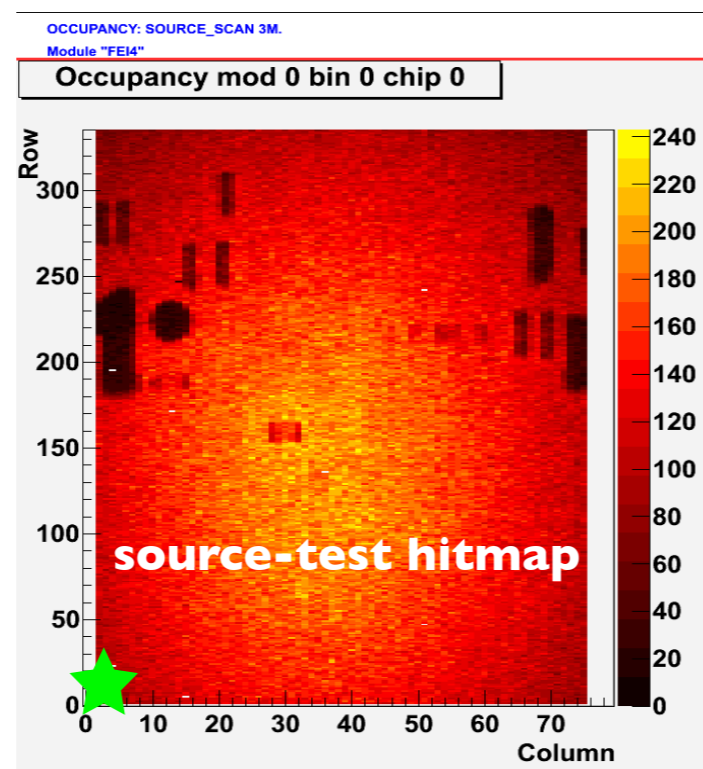
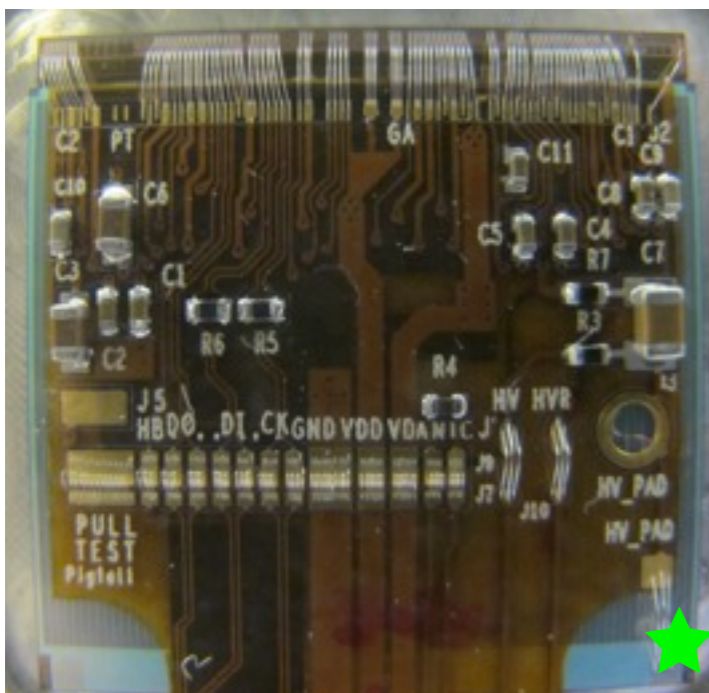
→ Sensor productions completed for both sensor technologies

Mixed scenario : Planar (75%) and 3D (25%)



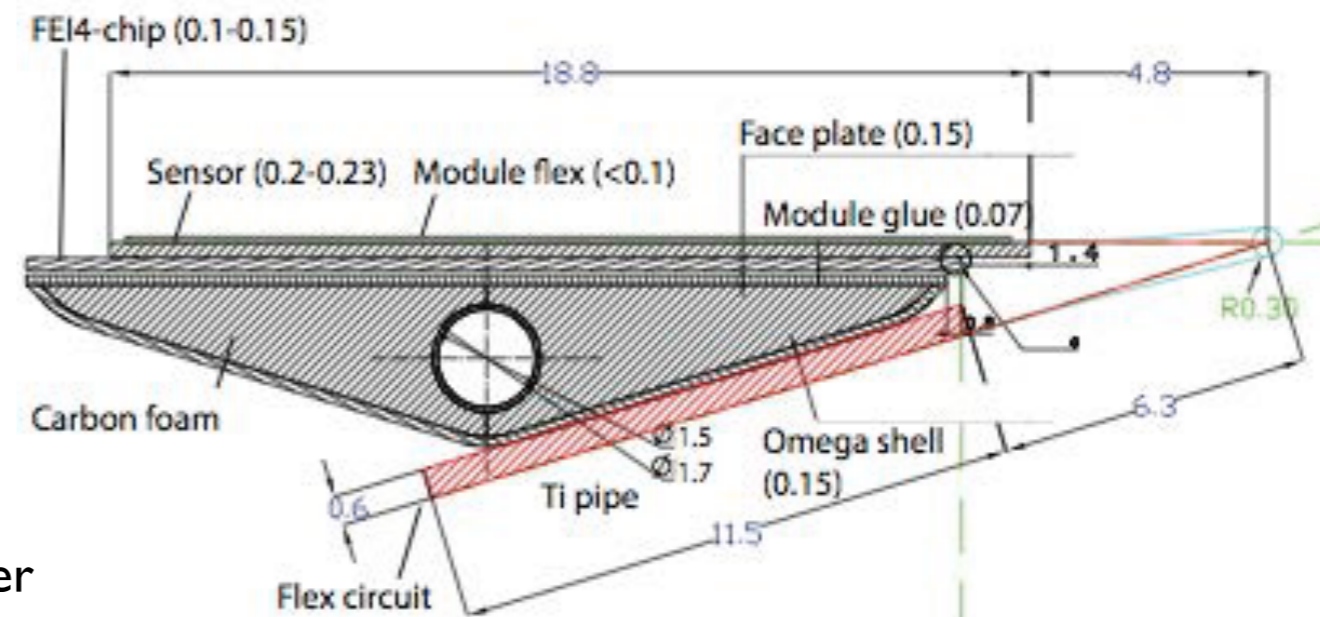
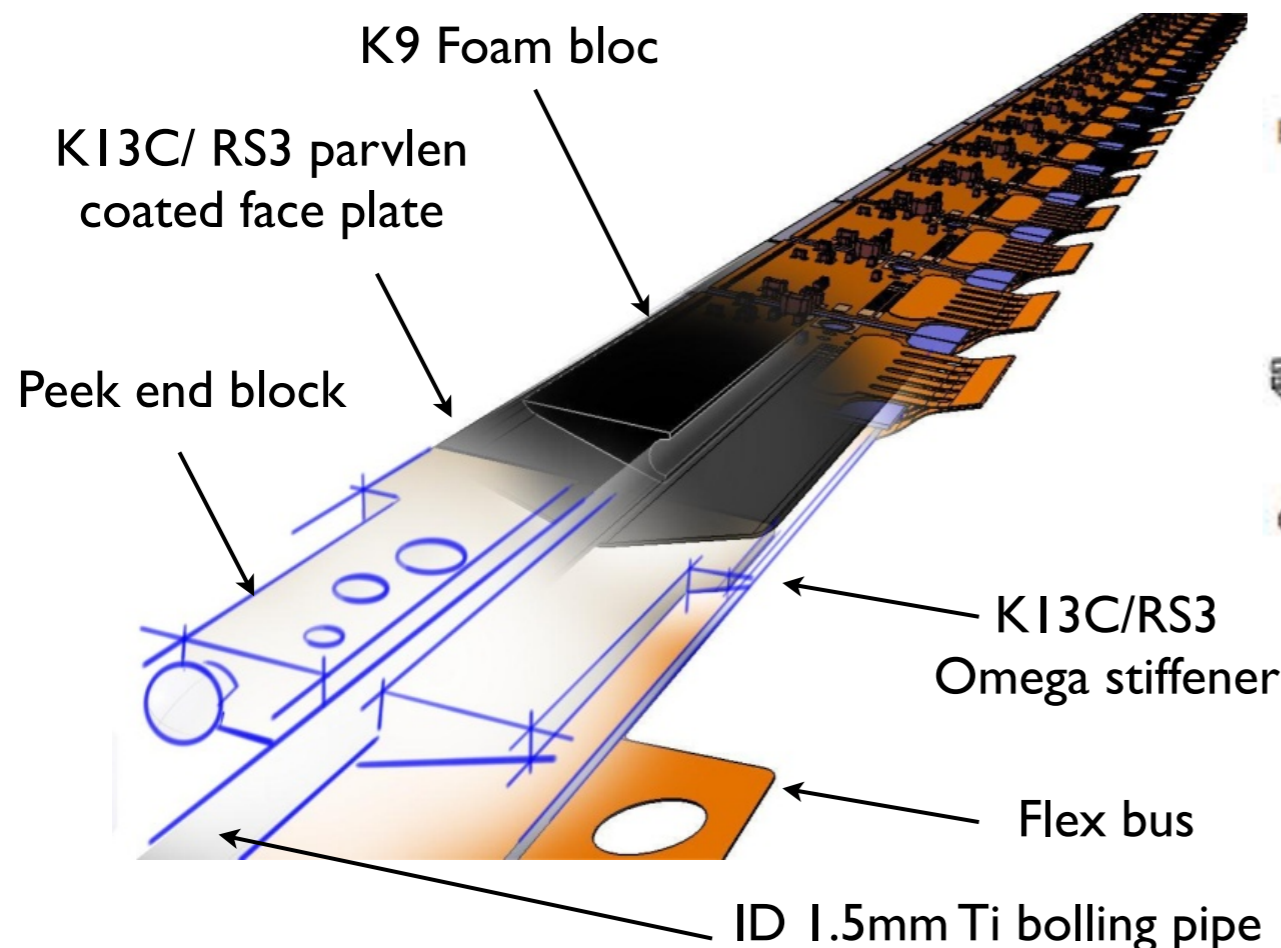
Fully assembled module

- Finished successfully pre-production equipped with FEI4-A&B
 - test final module design
 - prepare and test assembly and QA procedure
 - lab-tests with calibration, Am24I and Sr90
 - good performance so far
- Started production equipped with FEI4-B



Local support - *Stave*

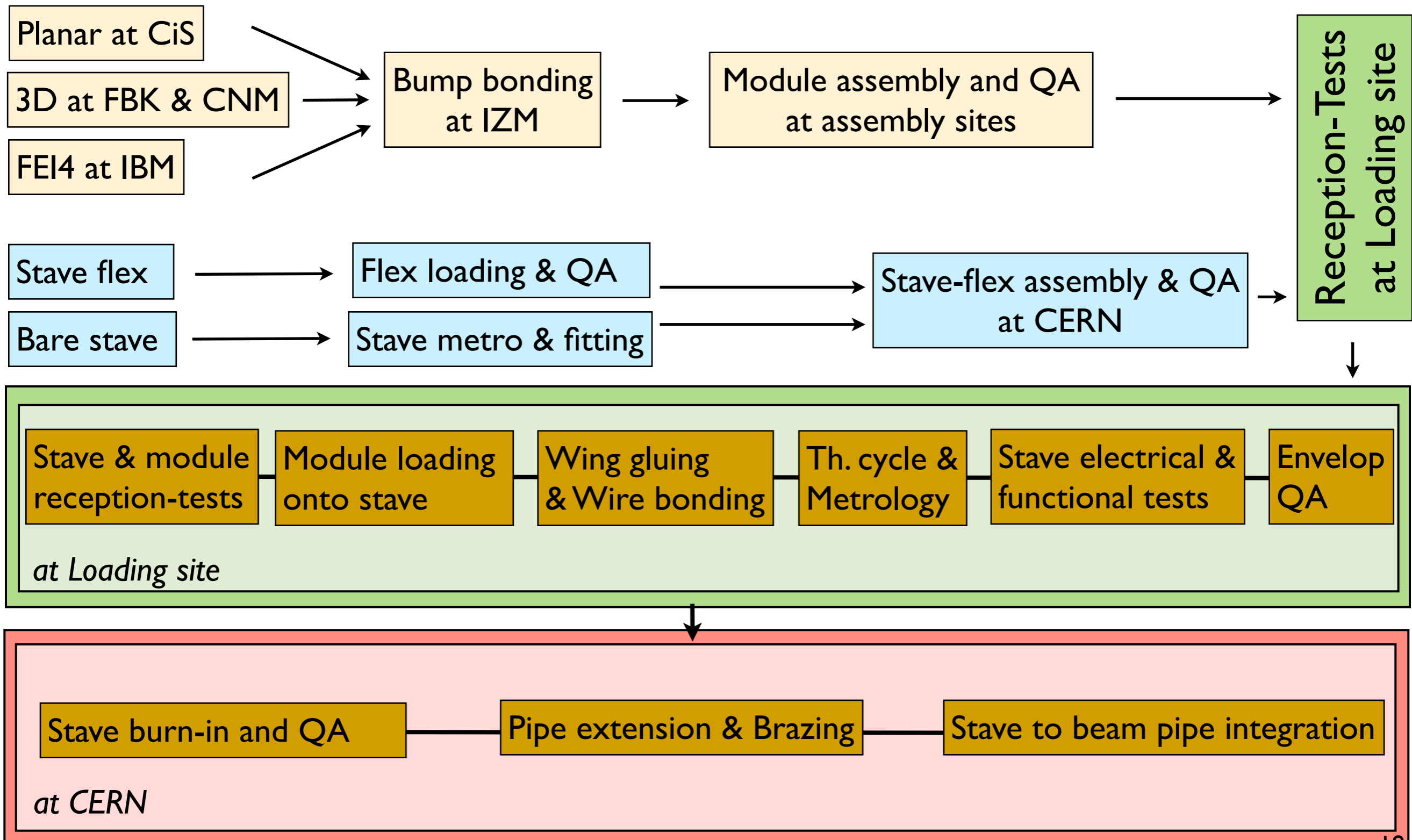
- Carbon-fiber support structure with minimal material budget $X/X_0 \sim 0.6\%$ for support and cooling
- Optimized stiffness and thermal conductivity
- Match thermal expansion
- Material qualification for use in high-radiation environments (300 Mrad)
- Detector cooling with a CO_2 system working -40°C to minimize the leakage current of the sensors



IBL Stave prototypes

- Loaded 3x prototypes and 1x production staves so far:
 - Stave -1: equipped with prototype flex, digital modules (dummy sensors + FEI4-A), temporary services.
 - Stave 0-A: as close as possible to production stave scenario, equipped with real modules with FEI4-A on board.
 - Stave 0-B: very close to the production stave, equipped with real modules with FEI4-B on board.
 - *Stave 1: production stave under loading ...*

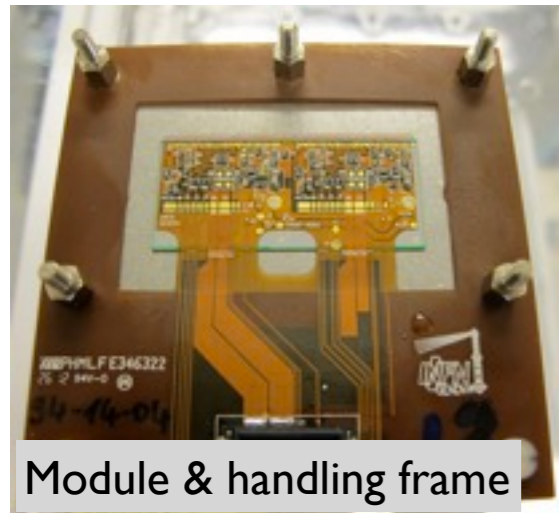
Production flow overview



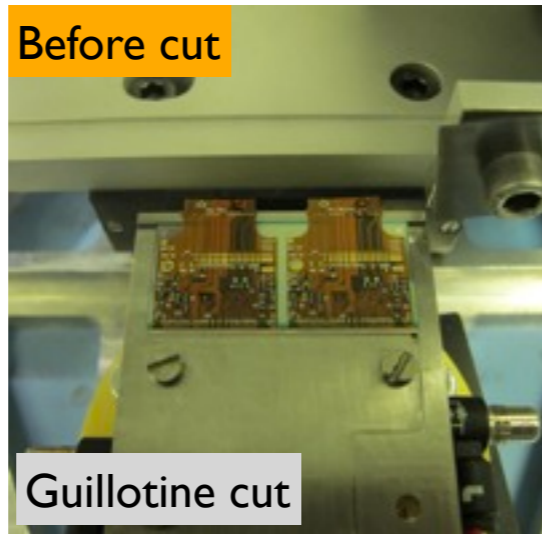
Loading procedure

1. Module reception-tests & module selection
2. Stave inspection, metrology, thermal cycling, metrology
3. Loading - one side after the other
4. Wing attachment
5. HV insulation insertion + spacer for wire bonding protection
6. Wire bonding and pull test
7. Stave electrical/functional tests one side after the other
8. Metrology survey
9. Thermal cycling
10. Metrology survey
11. Final stave electrical/functional tests
12. Stave envelope check
13. Shipment to CERN for QA & Integration

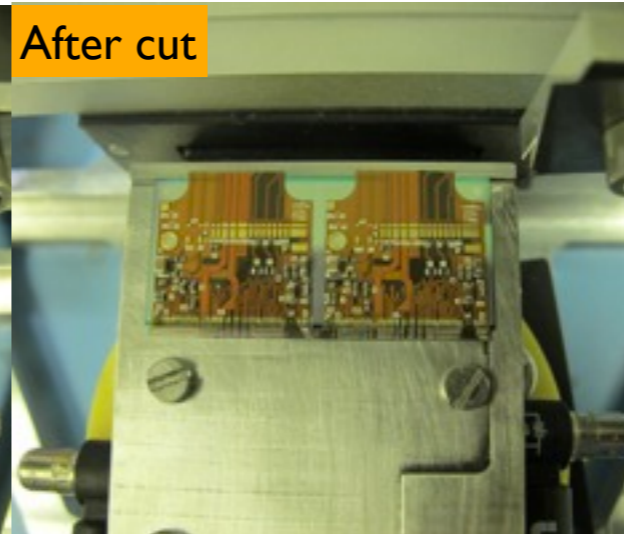
Loading procedure



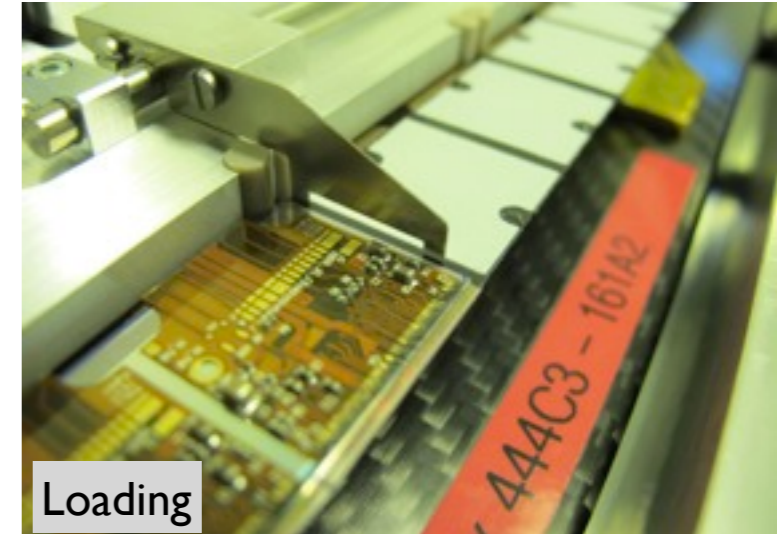
Module & handling frame



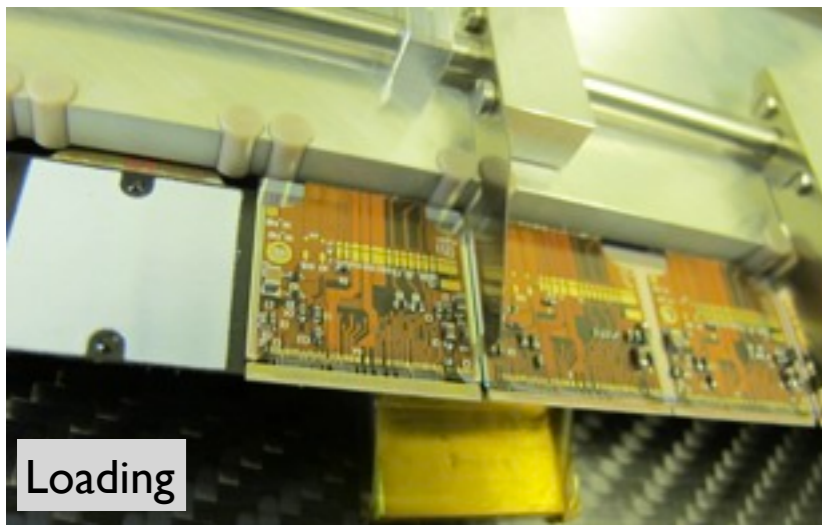
Guillotine cut



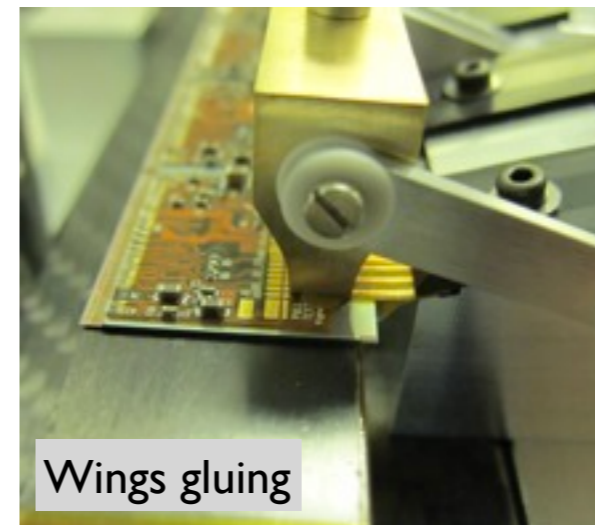
After cut



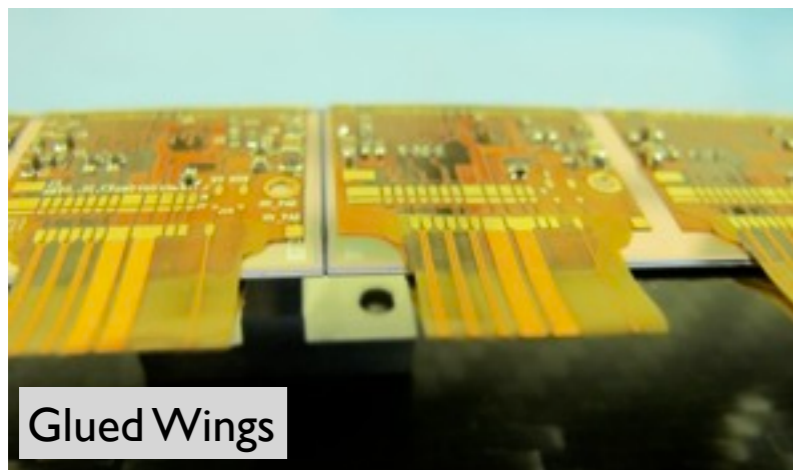
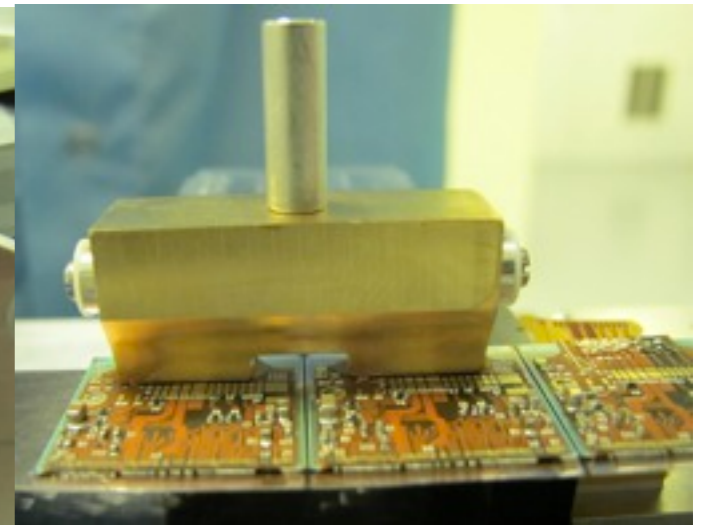
Loading



Loading



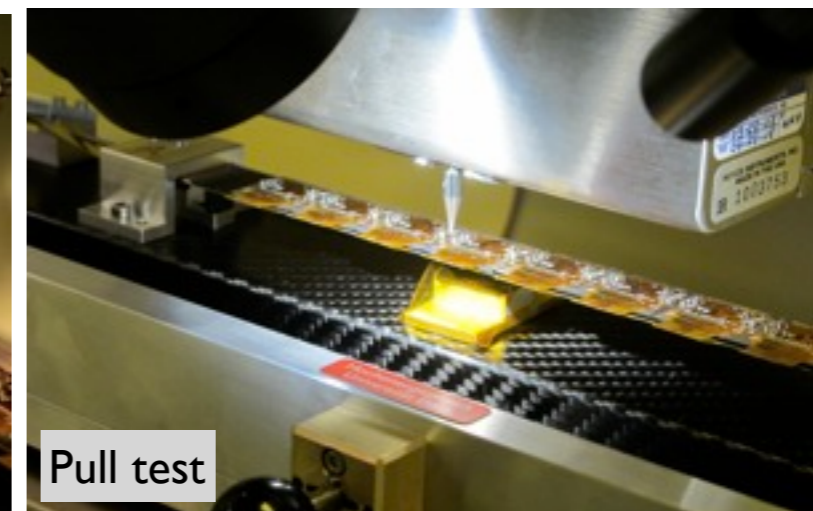
Wings gluing



Glued Wings



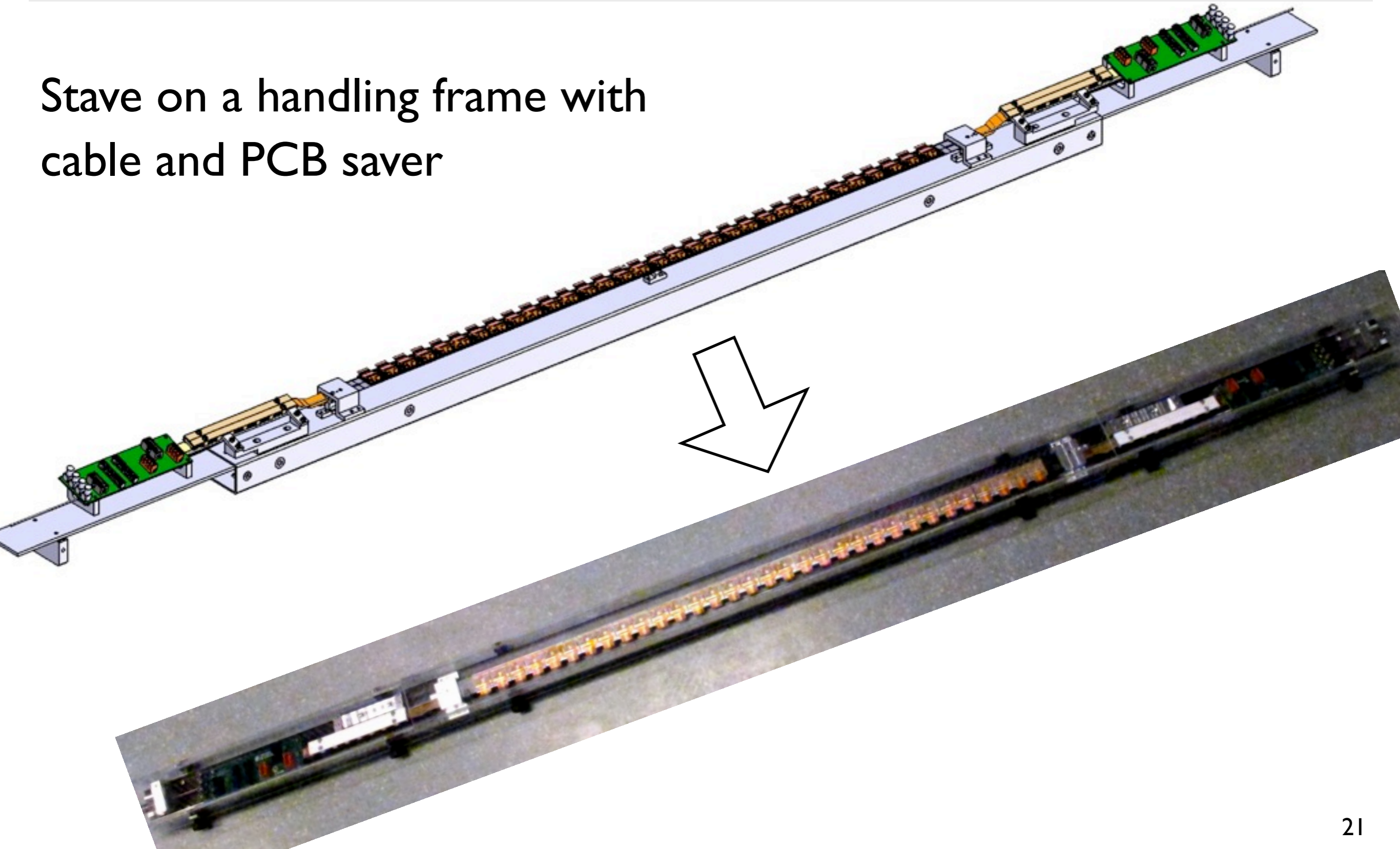
Wires bonding



Pull test

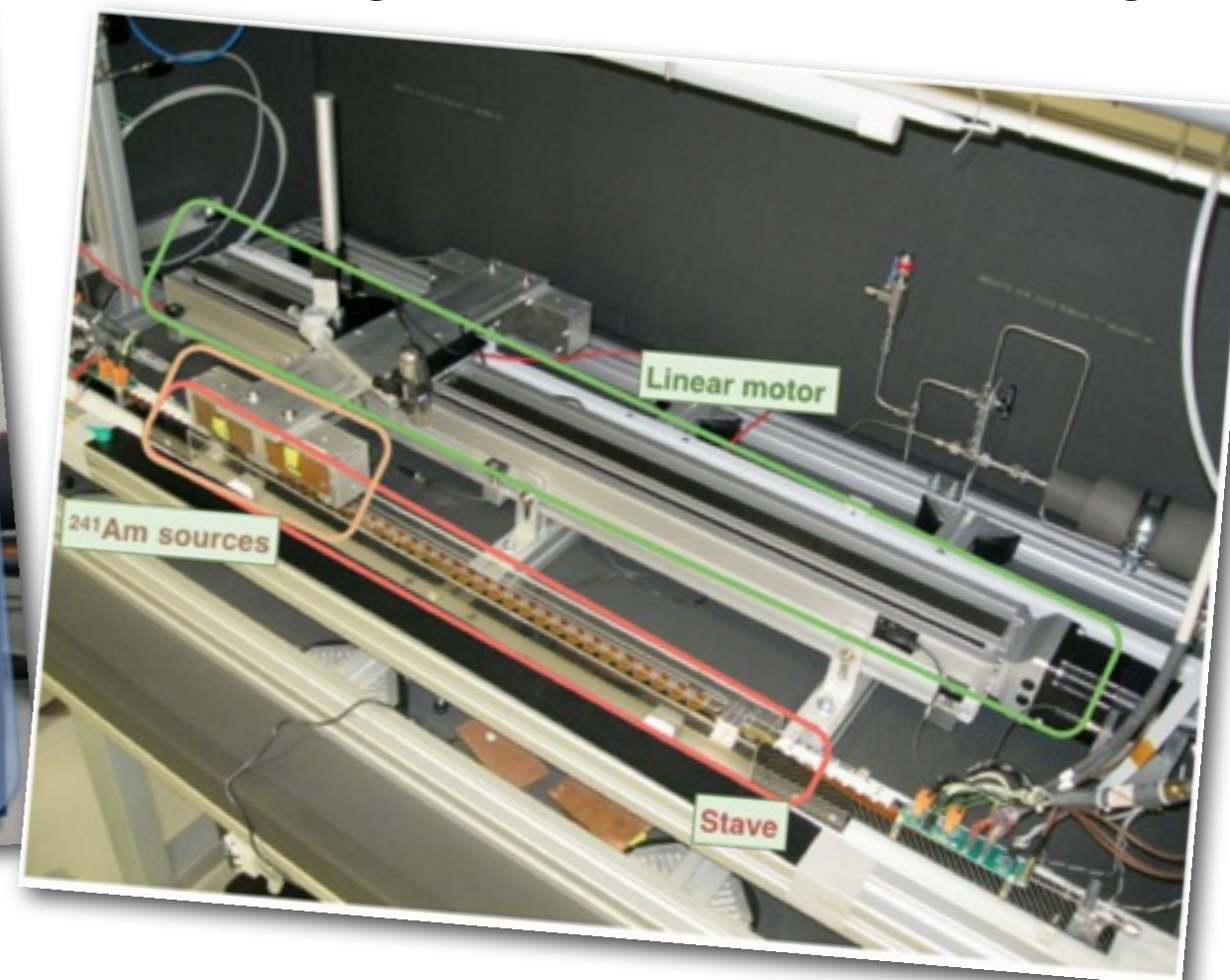
The Stave prototype

Stave on a handling frame with cable and PCB saver



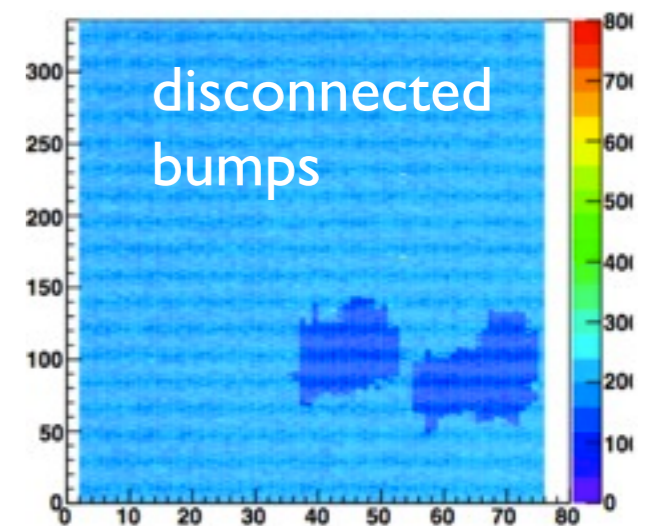
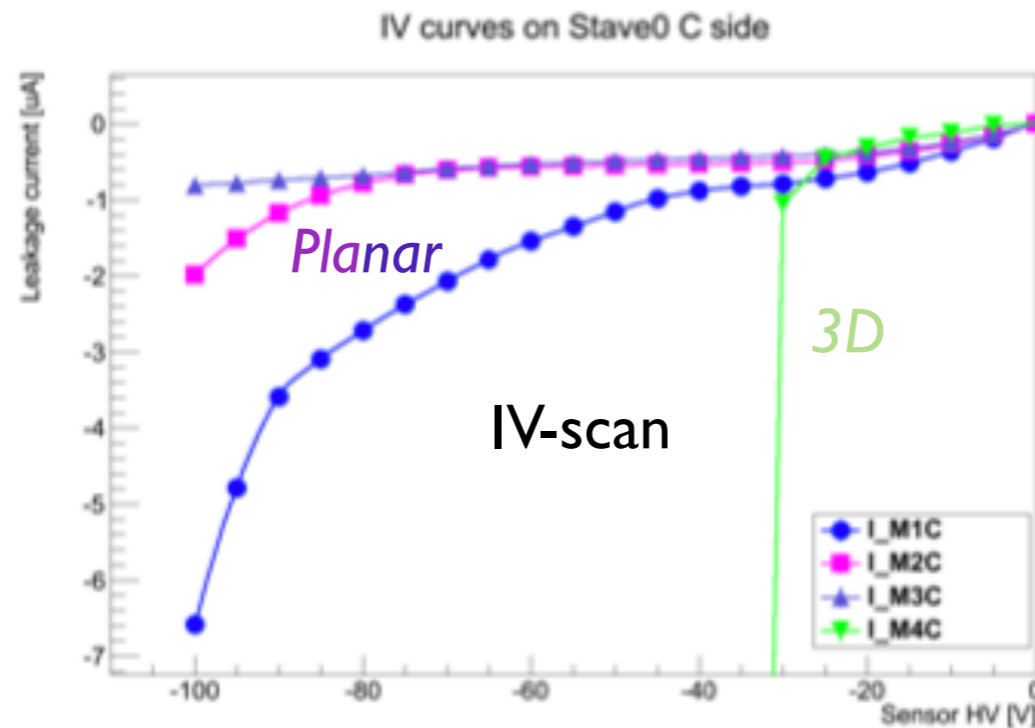
Stave System-test and QA

- Two systems (based on CO₂ cooling plant):
 - one at Loading site for Stave QC
 - one at CERN ALTAS Cleanroom (SRI) for long-term QA and source-tests
 - ▶ stave-setup equipped for running two stave-tests in parallel
 - ▶ includes 2x Am²⁴¹ and 1x Sr⁹⁰ sources on linear stages with automated scanning

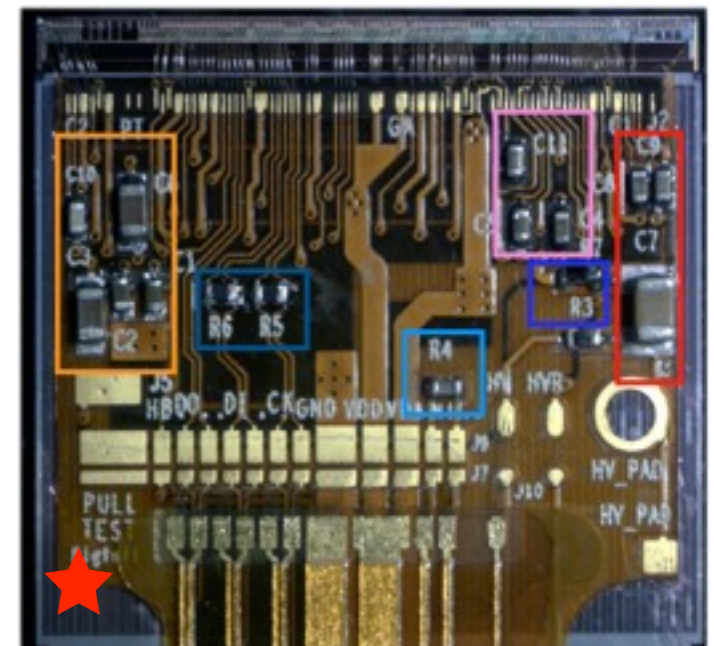
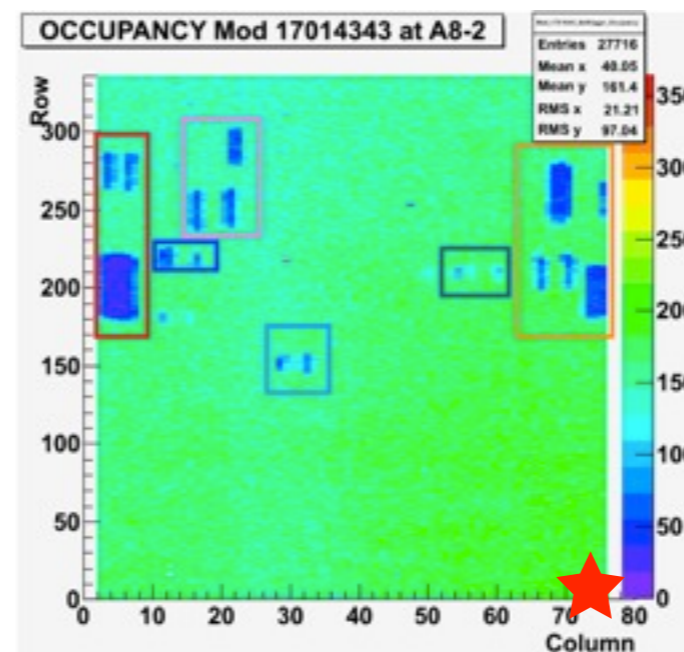


Stave prototype: test-results

- Several systematic (system-related) tests:
 - tuning at different threshold, gain, supply voltages
 - test of all modules IV
 - test of noise
 - LVDS signal transmission and power studies
 - source-tests of modules
 - cross-talk
 - test for merged and disconnected bumps

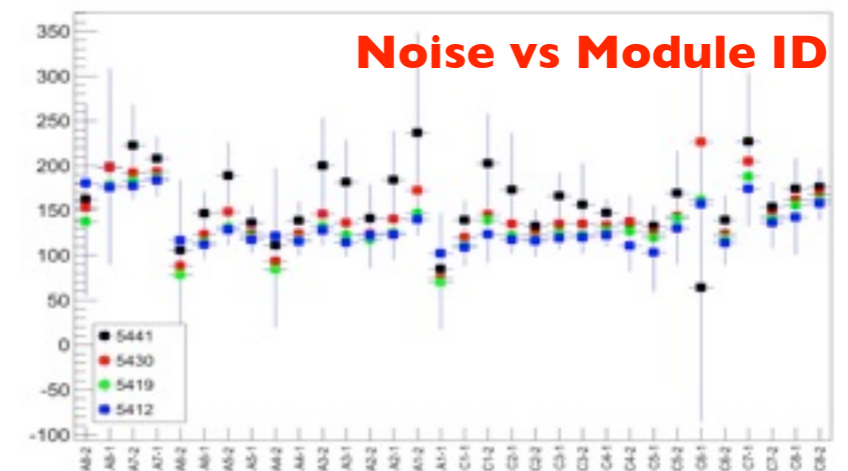
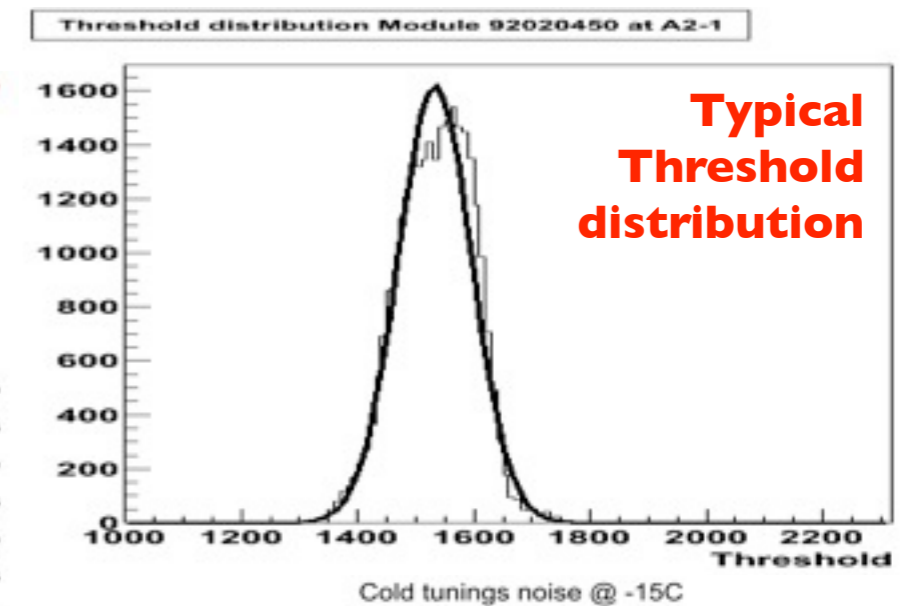
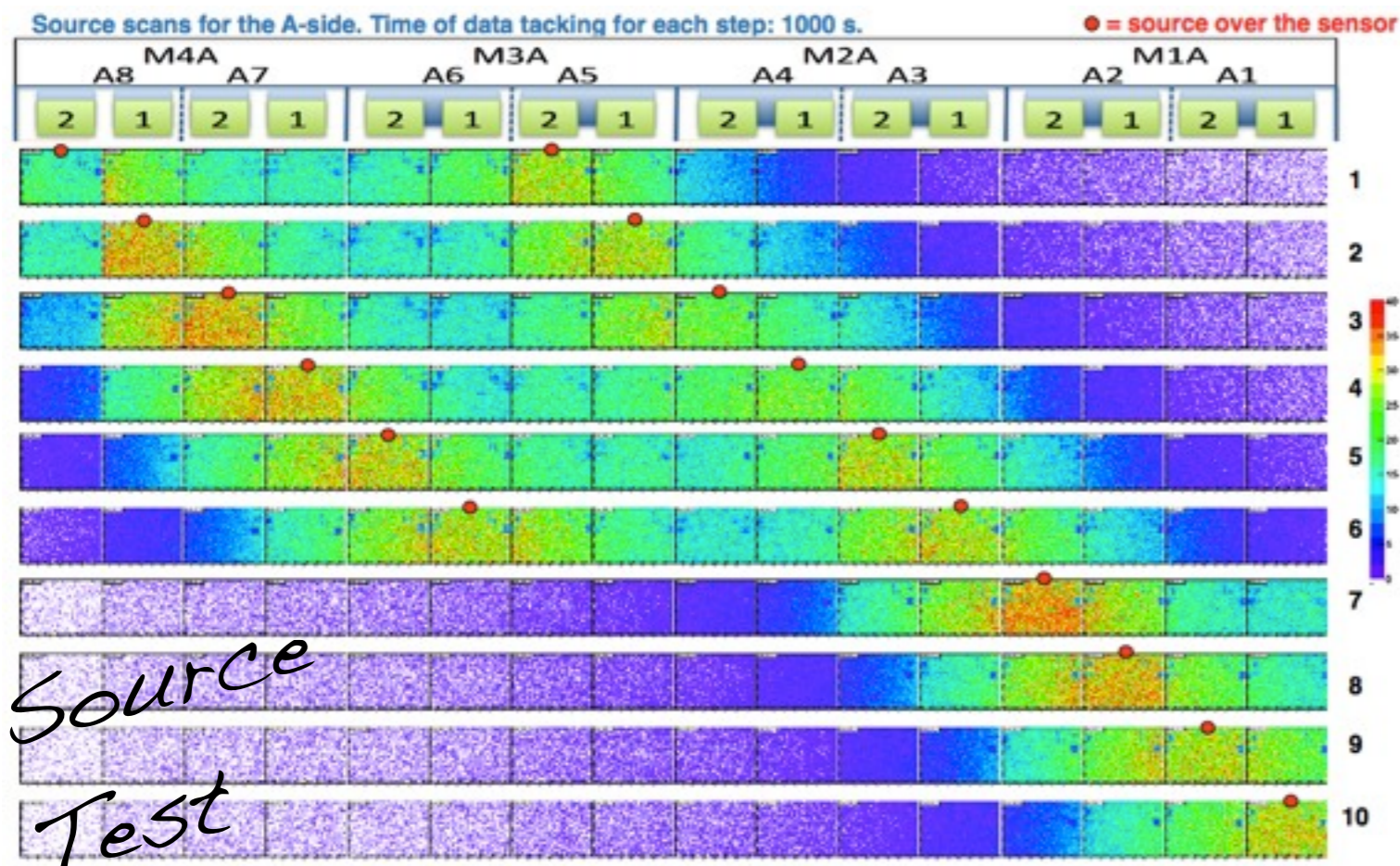


Am24I source-tests



Stave prototype: test-results

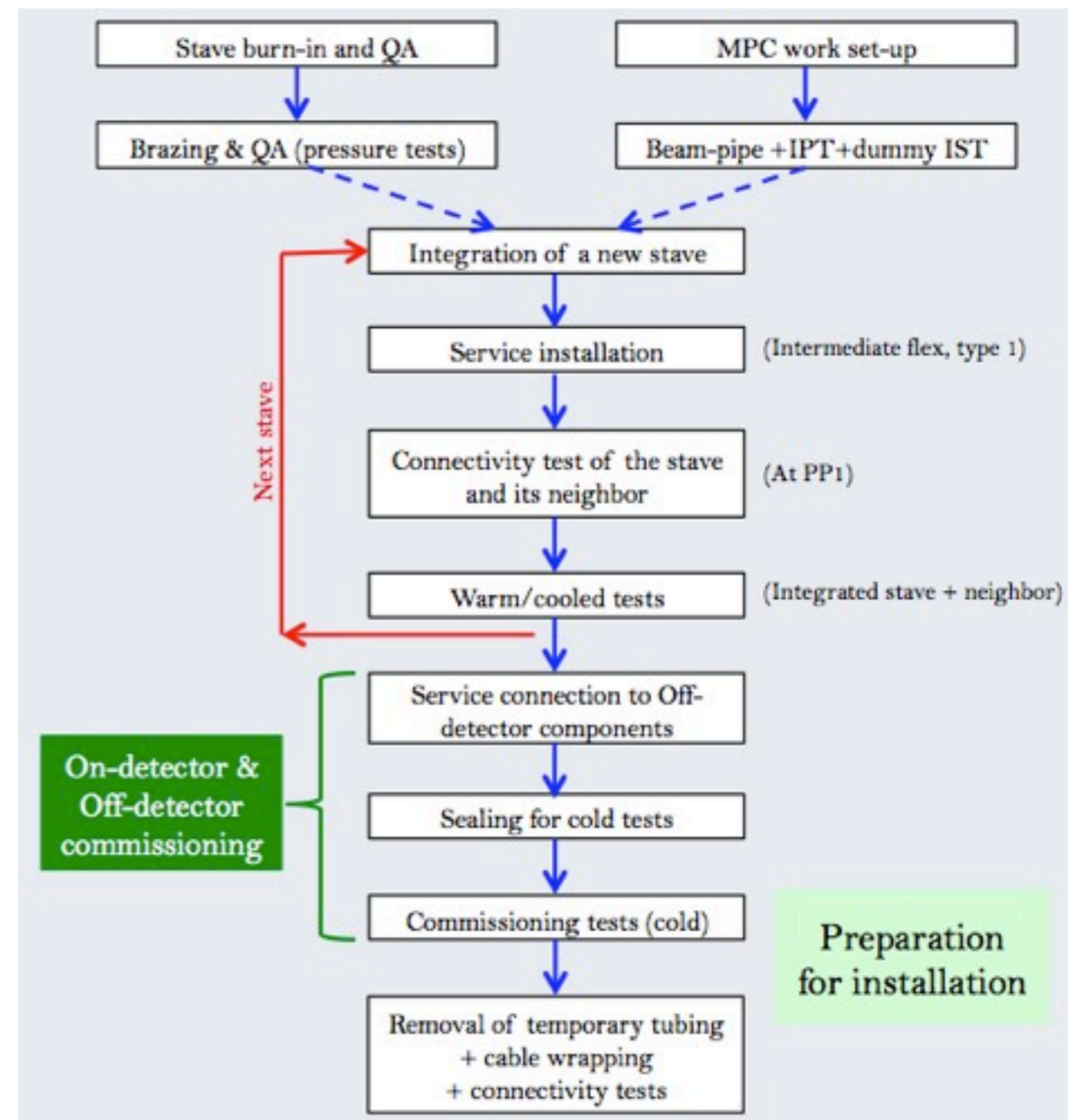
- General stave works in calibration and source scans
- All modules functional
- Operational threshold of 3000e with typical noise of 140e-160e
 - **found minimal threshold in cold stave tests of 1500e**



Stave Testing & Integration

- Integrate all 14 staves onto beam-pipe
 - including services
 - dedicated brazing stand
 - Multi-purpose container (MPC) for precision stave loading
- Commissioning each stave before integration (stave testing stand), and after with each integration
- Full 4th layer On and Off detector commissioning after all staves integrated

To repeat 14 times



IBL schedule overview

Not all IBL topics	2013								2014				
	Q1		Q2		Q3		Q4		Q1		Q2		
Module production	■	■	■	■	■	■	■						
Stave production	■	■	■										
Flex production	■	■	■	■									
Stave loading & QC		■	■	■	■	■	■						
Stave QA	Stave 0		■	■	■	■	■	■					
Type 1 production and tests	Prototypes		■	■	■	■	■						
Beam pipe preparation	■	■	■										
IPT assembly	■	■	■	■									
MPC assembly	■	■	■	■	■								
Integration tool	■	■	■	■	■	■							
Brazing stand installation in SR1				■	■								
Stave cooling extension - Brazing	Tests and validation					■	■	■					
Stave integration						■	■	■					
Type 0/1 integration						■	■	■					
Stave tests						■	■	■	■				
Prep. for commissioning work									■				
Full commissioning test									■	■			
										Option 1	Option 2		
IBL inside Pixel detector										◇	◇		
Installation of the Pixel detector											◆		

D. Ferrere, Pixel Week (12/2/2013)

Summary

- The FEI4 readout chip is qualified and delivered
- Planar n-in-n and 3D are qualified and manufactured
- Module hybridization is in production
- Mechanics and service are qualified and in production
- Evaluation of pre-production staves done
- Assembly stave production started

References

- *ATLAS Insertable B-Layer Technical Design Report.* CERN-LHCC-2010-013
- *ATLAS Insertable B-Layer Technical Design Report Addendum.* CERN-LHCC-2012-009
- *Prototype ATLAS IBL Modules using the FE-I4A Front-End Readout Chip.* JINST (2012) 7 P11010.